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Examiner: Wilson, L.

Atty. Dkt. No. 5298-05700

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Kevin L. Daffer

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FEB 25 2003

**TECHNOLOGY CENTER R3700**

This paper is submitted in response to the Office Action dated November 20, 2002 to further highlight reasons why the application is in condition for allowance.

Please replace pg. 4, lines 9-25, with the amended paragraph below. A “marked-up” version of each amendment is including in **Attachment A**.

In order to increase the effectiveness of a polishing pad in a polishing system, the polishing pad may be cleaned periodically. Such a process is typically a sporadic manual process which involves shutting down the polishing system and depositing water upon the pad in an effort to suspend the particles in solution and subsequently wash them away. Unfortunately, such a process typically does not remove all